

Are Spring Probes Valid Below 400 Micron Pitch?



Jon Diller
Dr. Jiachun (Frank) Zhou
Interconnect Devices, Inc.



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Probably not.

(but wait, there's more)

Market Requirements

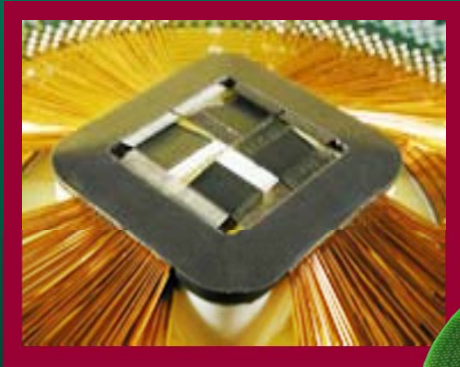
Primarily WLCSP (now) and PoP (pretty soon)

- 0.3 pitch WLCSP bump $\varnothing 0.21$; 0.2 with $\varnothing 0.115$ extant
- PoP primarily lands under solder resist or balls

Test Technology Status Quo

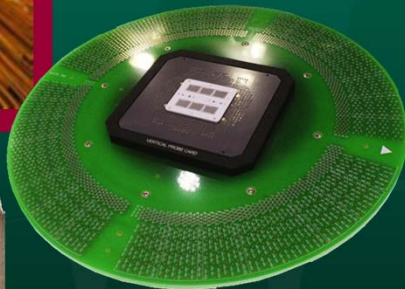
- WLCSP on probers, inline cleaning, >200 UPH, expected cycle life >500K
- PoP in pick-and-place applications, offline cleaning, triple-digit UPH, expected cycle life 100-250K

Current Methodology



Cantilever and vertical solutions

- ◆ Limited array depth
- ◆ Limited compliance
- ◆ Difficult to repair
- ◆ High cost of use



'Floating' spring probes

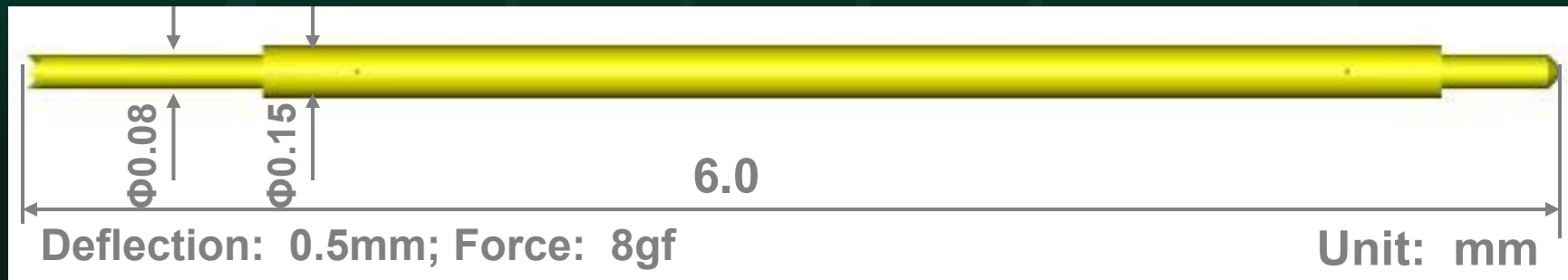
- ◆ Very reliable
- ◆ Excellent RF performance
- ◆ Easily maintained
- ◆ Limited to 400 μm pitch



Current Methodology

Sub-400 Spring Contact Probes

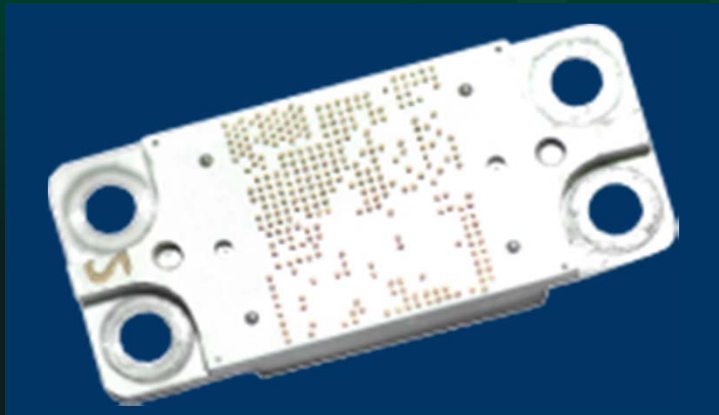
- Similar technology available from several vendors
- Highly compliant at the expense of length
- Field serviceable...
- Difficult to clean
- Fragile



Monet

Embedded Barrel:

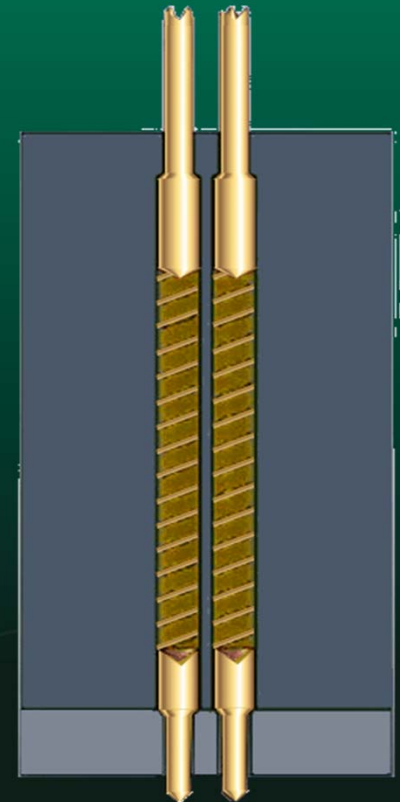
- ◆ High contact density
- ◆ Short length
- ◆ Good compliance and force
- ◆ HVM robustness
- ◆ Easy maintenance
- ◆ Excellent accuracy



Conductive Cavity



Components



Shift in Diameters

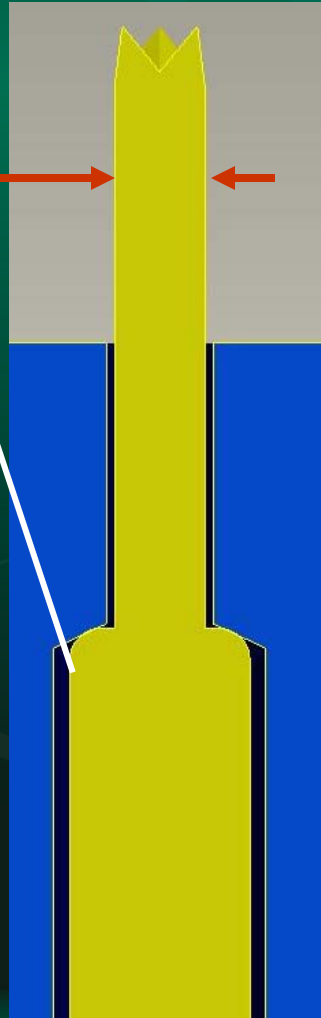
Traditional Probe

Embedded Contact

80 μm (really tiny)



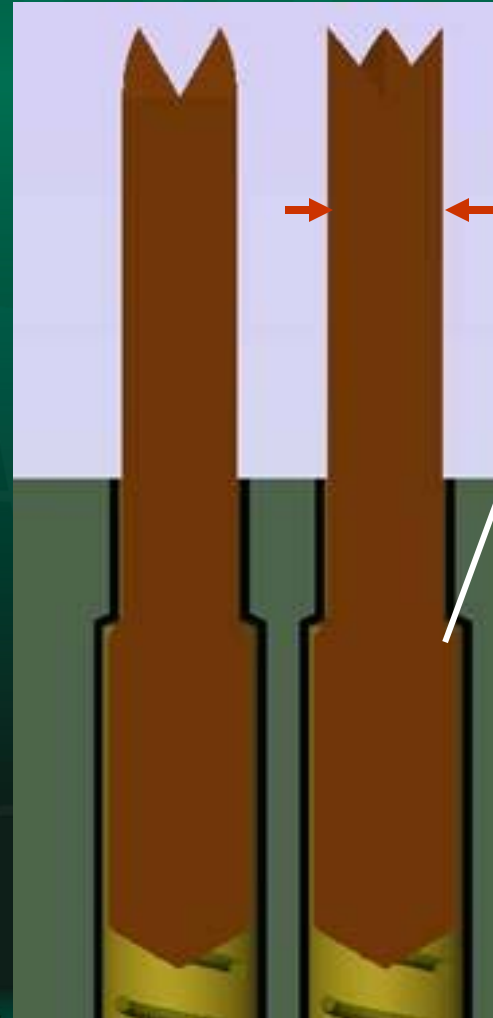
30 to 50
micron gap
between
barrel and
cavity hole



110 μm
(comparable
to 0.4)



No gap
between
barrel &
socket
body



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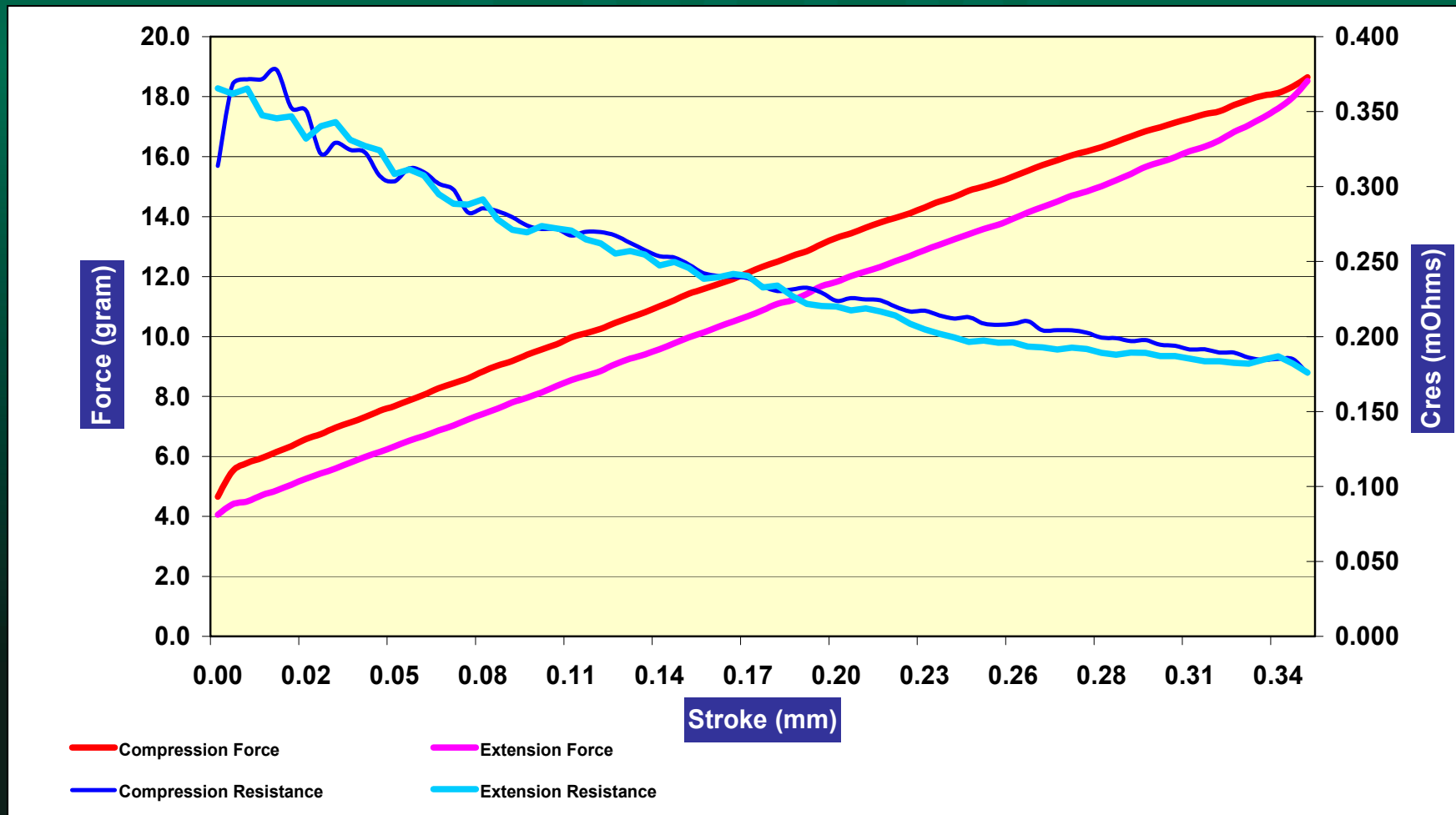
Alignment Improvement

Several Factors

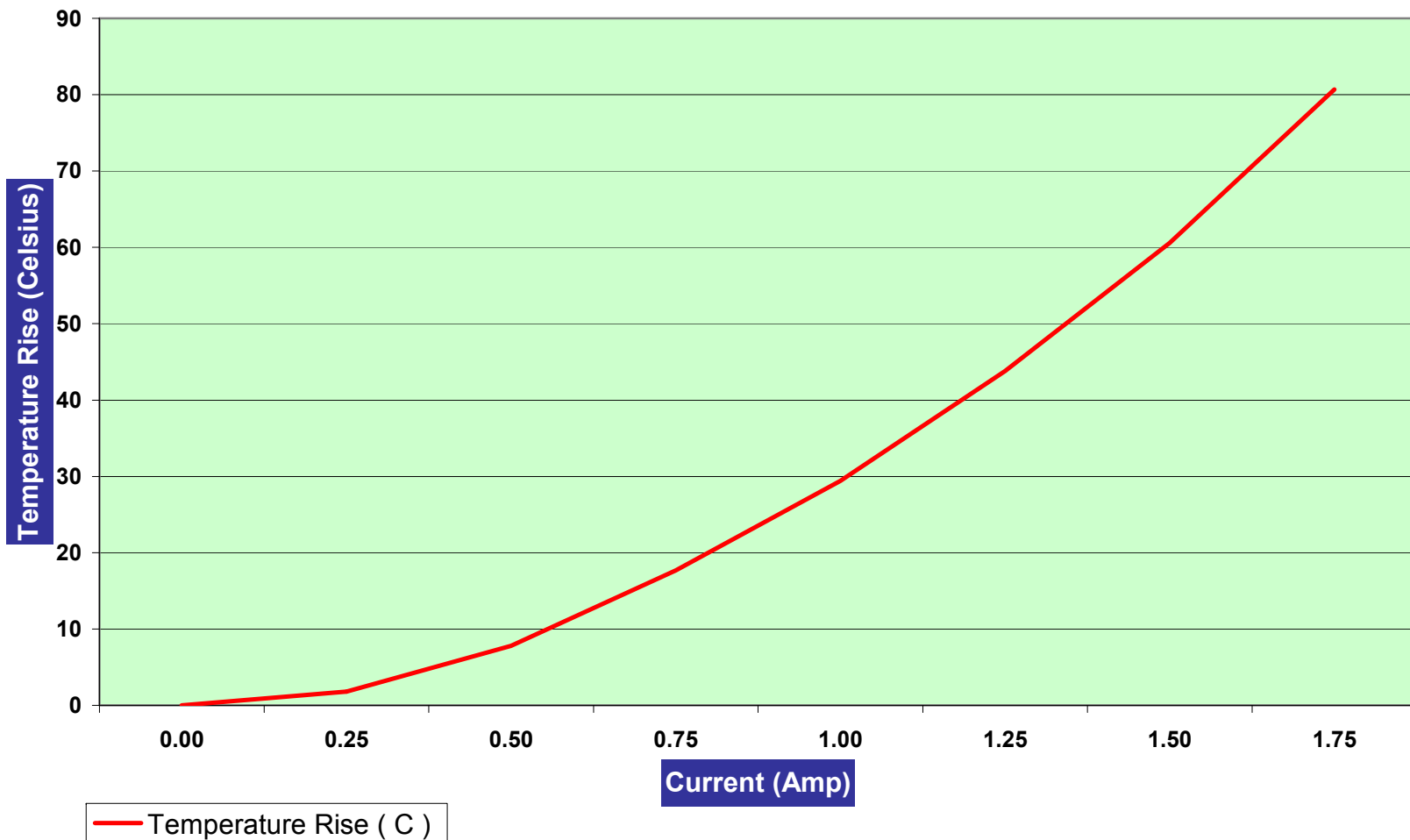
- One less gap
- Improved aspect ratio of hole in plastic
- Larger diameter plunger is more concentric
- Electroforming produces high concentricity of 'barrel'
- Retainer plate true position does not affect top plunger

More Force, Stable Resistance

17 gf versus 8 gf. large 'sweet spot'

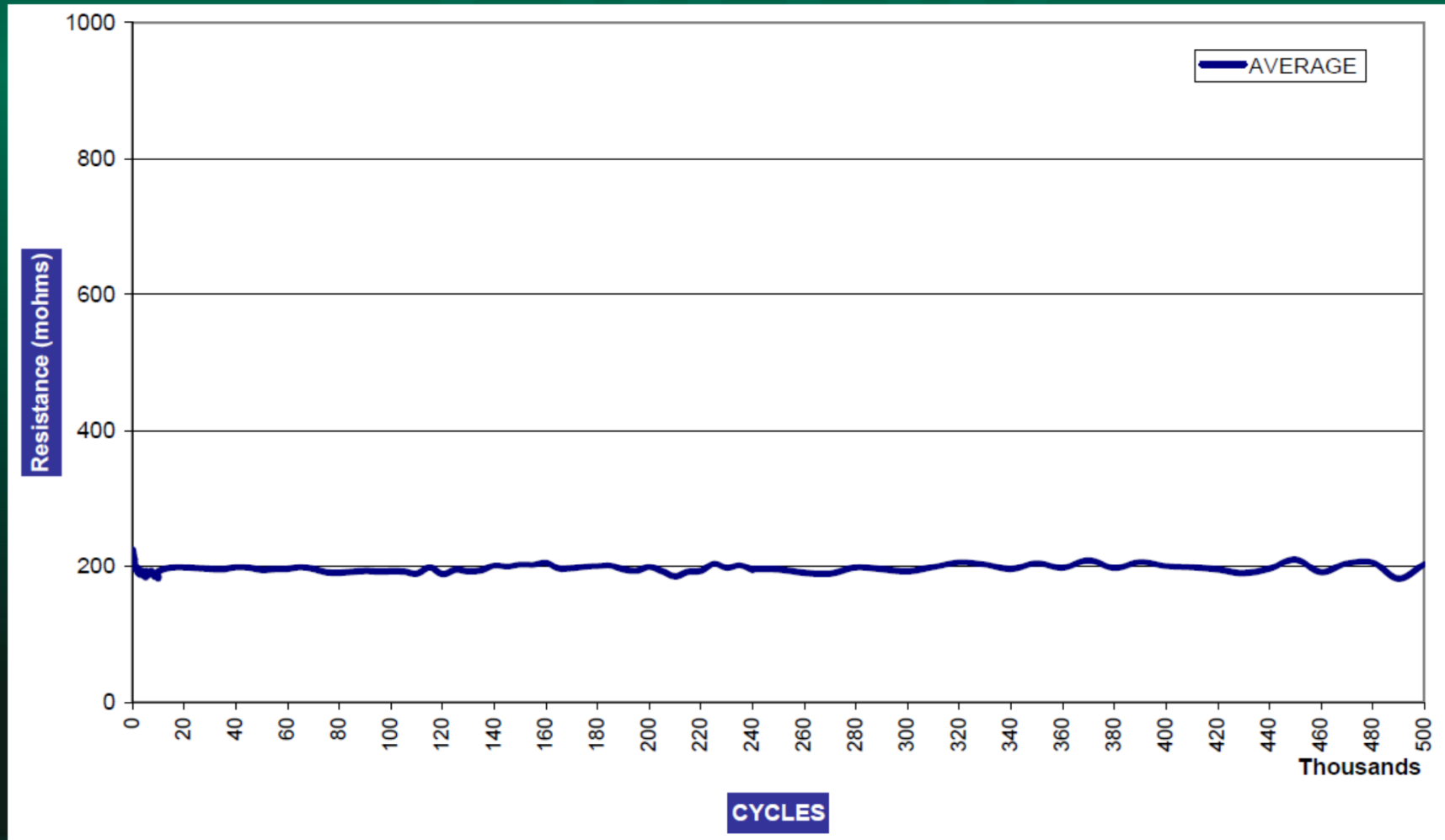


Stable Resistance, High Current Carrying Capacity



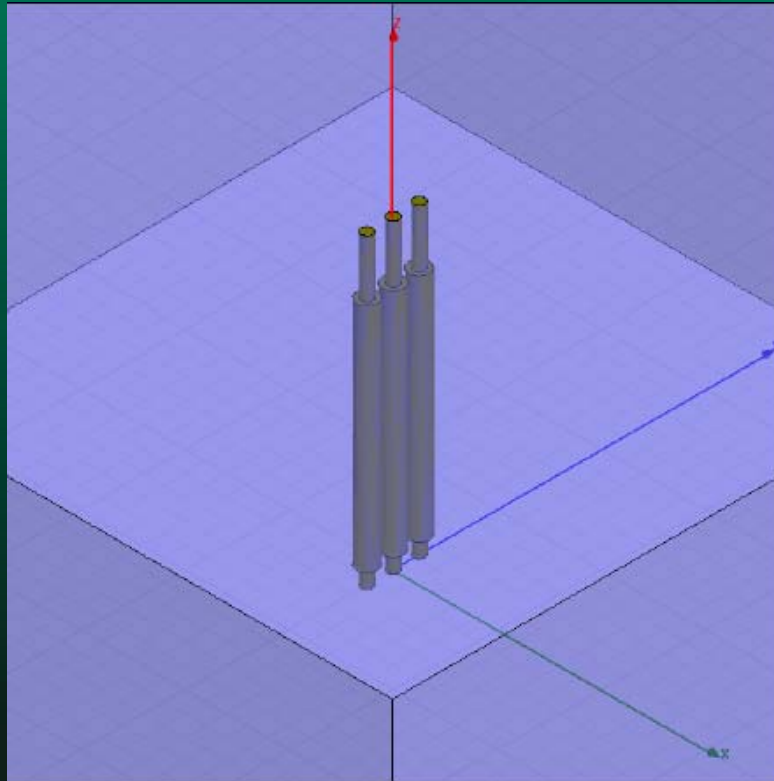
Extended Mechanical Life

Stable performance through 500K touchdowns



Signal Integrity Methodology

Device Side



Board Side

Single Ended



Differential Pair

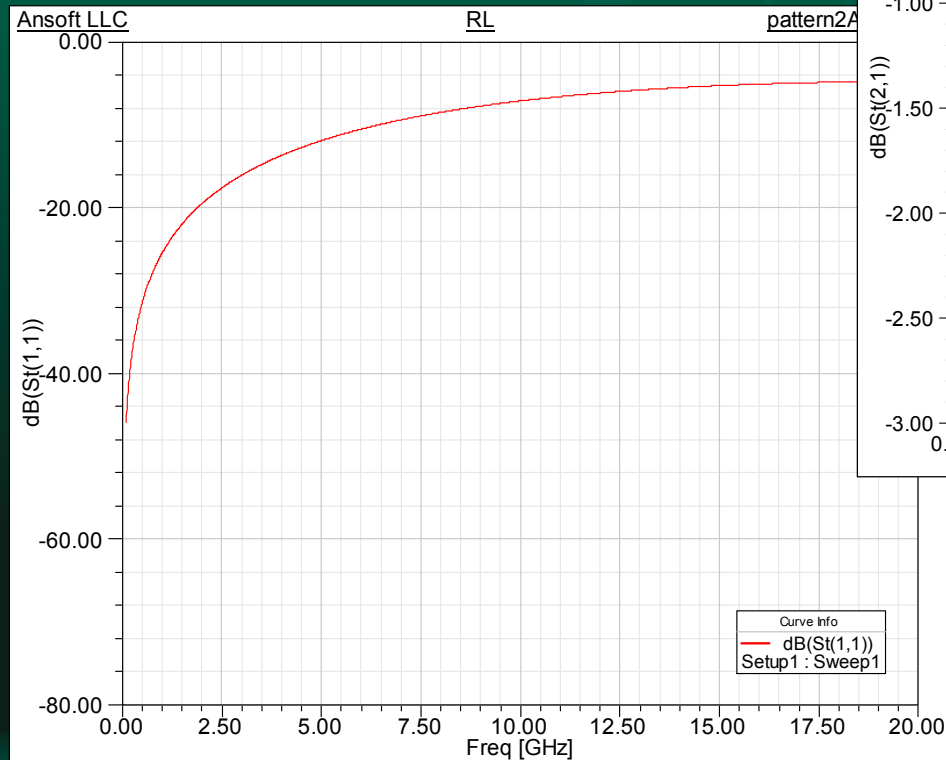


Analog Behavior

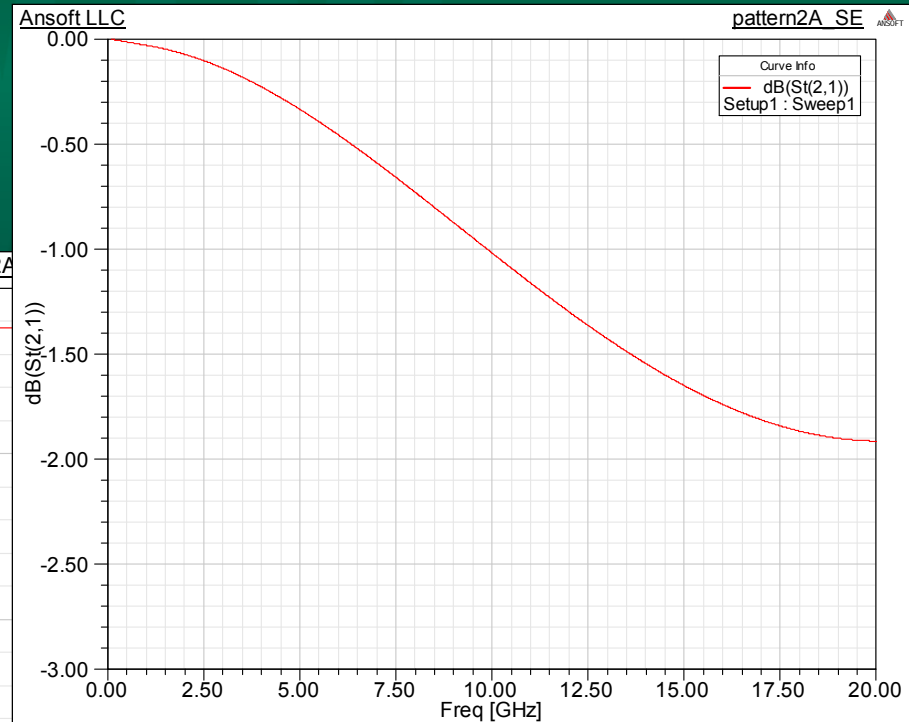
10 GHz BW

@ 250 μm

Return Loss



Insertion Loss



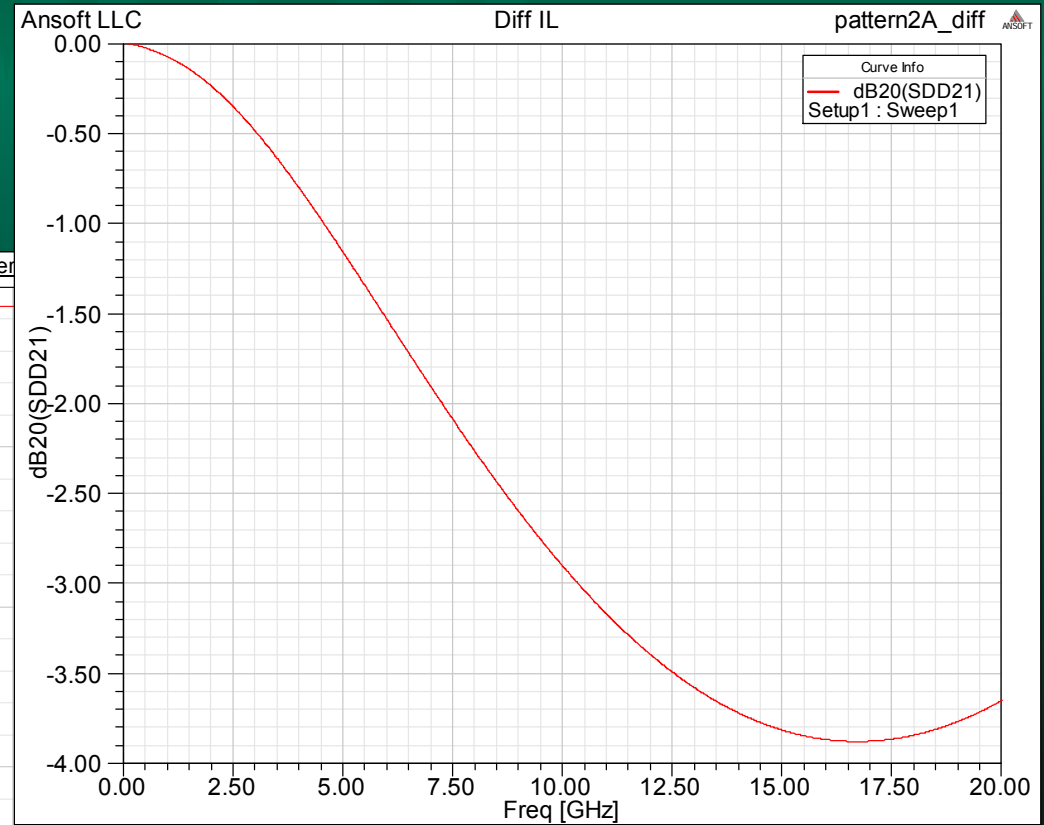
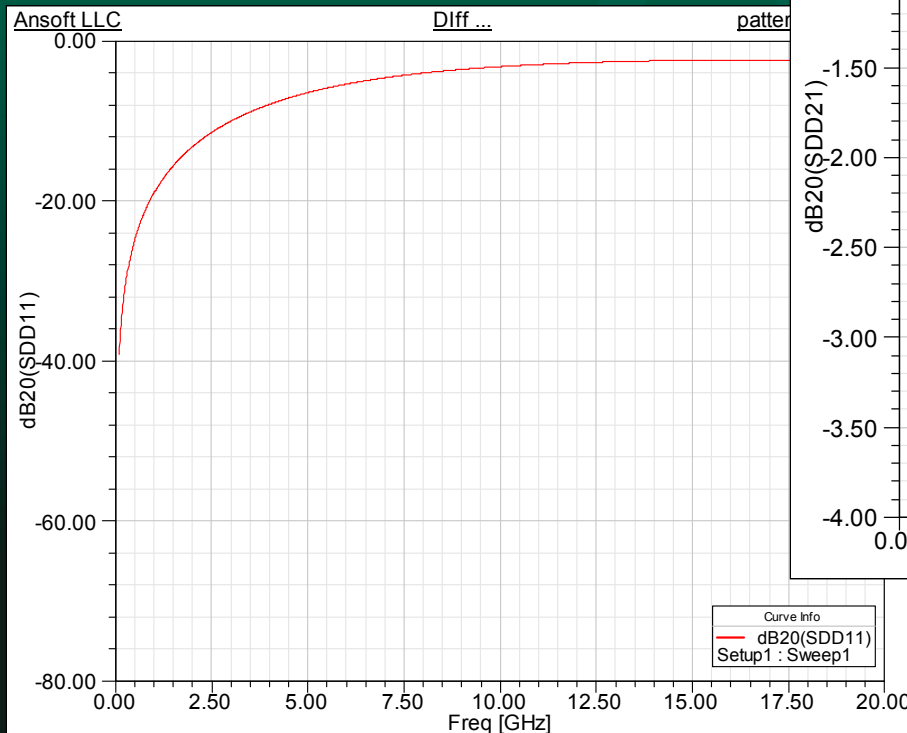
Differential Behavior

3 Gbps

@ 250 μm

Return Loss

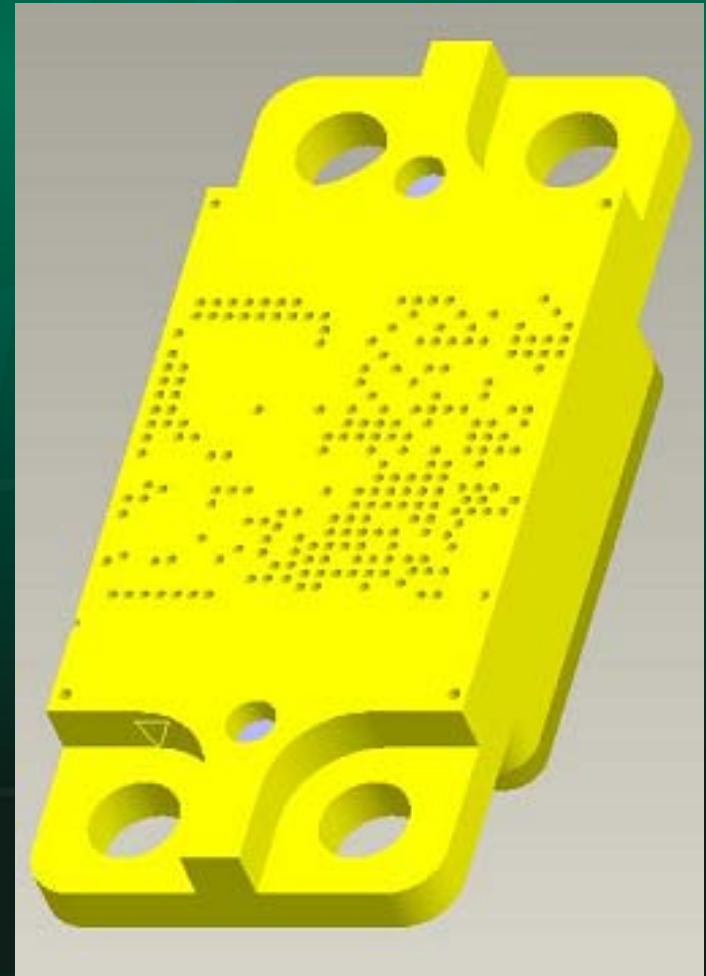
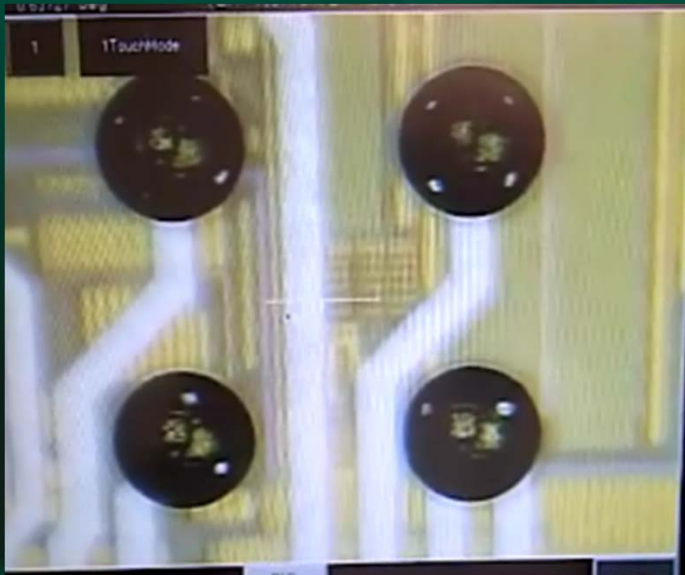
Insertion Loss



Alpha Program

Validation of manufacturing capability and alignment

- >200 pins per site, 4 sites, 0.25 mm pitch
- Aligned well, passed initial electrical tests



Summary

Spring contact probes are a preferred technology for P0.4mm pitch but are challenged at finer pitches.

By embedding the probe barrel in the contactor body significant gains can be made in robustness, alignment, and signal integrity

This approach has potential for all WLCSP pitches: 250 μm , 200 μm , 180 μm , 150 μm

Acknowledgements

The following persons were instrumental in the creation of this paper:

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Thank You!

Your questions are welcome.